606-nm InGaN Amber Micro-Light-Emitting Diodes With an On-Wafer External Quantum Efficiency of 0.56%

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Abstract—We demonstrated amber InGaN 47 × 47 μ m² micro-light-emitting diodes (μ LEDs) with the peak wavelength of 606 nm and full-width at maximum (FWHM) of 50 nm at 20 A/cm². The amber μ LEDs exhibited a 33-nm blue-shift of the peak wavelength and obtain broader FWHMs to approximately 56 nm at 5 to 100 A/cm². The peak on-wafer external quantum efficiency was 0.56% at 20 A/cm². The characteristic temperature was 50–80 K at 20 to 60 A/cm² but increased to 120–140 K at 80 to 100 A/cm². The strong increase in the characteristic temperature from 60 to 80 A/cm² could mainly be attributed to the saturation of the Shockley-Read-Hall non-radiative recombination at high current densities.

Index Terms—InGaN, amber micro-light-emitting diode, on-wafer external quantum efficiency, characteristic temperature.

I. INTRODUCTION

D UE to their high brightness levels, long lifetime, large modulation bandwidth, and small form factors, InGaNbased micro-light-emitting diodes (μ LEDs) have achieved expanding interests in many newly-emerging applications such as micro-displays in wearable and smart electronics, visible light communication, and biomedical sensors [1,2]. Although InGaN blue and green LEDs have been commercialized owing to their mature technology and reliability, many studies have reported that the external quantum efficiency (EQE) of InGaN μ LEDs decreases with chip size [3]–[5]. This size dependence of the EQE was caused by the non-radiative recombination at the edge of the device active region [6]–[8], which could be eliminated or avoided by using a combination of chemical treatment and atomic-layer deposition sidewall passivation [9] or the bottom-up growth method to form μ LED mesas [10].

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Another important issue to consider is red, green, and blue μ LEDs for full-color micro-displays. Generally, InGaN LEDs suffer from a significant reduction in EQE as the In content increases in InGaN quantum wells (QWs) [11]. EQE reduction can mainly be attributed to the degradation of the crystal quality for InGaN QWs because of the large lattice mismatch between high In-content InGaN and GaN templates [8]. To reduce lattice mismatch, a partially relaxed InGaN pseudo-substrate fabricated by Soitec was proposed for high In-content InGaN red LEDs [12]. Another lattice-matched InGaN template grown on ScAlMgO₄ (0001) substrates also proved to be capable of remarkably improving the internal quantum efficiency of InGaN QWs, showing the potential of these lattice-matched templates for long-wavelength InGaN emitters [13].

Recently, $6 \times 6 \mu m^2$ size 632-nm InGaN μ LEDs on porous GaN were demonstrated to have an on-wafer EQE of 0.2%, which was the first reported value for red μ LEDs with the dimension <10 μ m [14]. Besides, orange/red InGaN LEDs could realize high efficiency on silicon substrates [15] because the tensile strain of the GaN on silicon during growth was favorable for In incorporation [11]. Our group chose to adjust the thickness of the GaN on sapphire substrates to realize highly efficient InGaN red LEDs [16]. Besides, the proposed micro-flow growth method [17] and AlN/AlGaN strain-compensated barriers [18] were also useful for improving the crystal quality of high-In-content InGaN QWs.

For most micro-displays, μ LEDs need to be driven at low current densities. However, some applications such as head-mounted displays and image sources in projection systems, which need very high brightness levels, require μ LEDs to be operated at high current densities. Besides, the optogenetic stimulation of chrimson by μ LEDs also requires a minimal optical power density, which could not be realized at low current densities [19]. Because strong quantum-confined Stark effect (QCSE) in InGaN QWs makes a large blue-shift of the peak wavelength, InGaN long-wavelength-emitting μ LEDs operated at high current densities need higher In contents compared to μ LEDs operated at low current densities, which will be much more challenging.

In this work, we demonstrated 606-nm InGaN amber μ LEDs with dimensions of 47 × 47 μ m² at 20 A/cm². We examined the current–voltage (*I–V*) curve to investigate the leakage current and operating voltage of our μ LEDs. Optical properties, including the peak wavelength, full-width

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Fig. 1. Schematic structure of InGaN µLED devices.

at half maximum (FWHM), light output power, and on-wafer EQE of the amber μ LEDs, were characterized by on-wafer testing. We finally measured temperature-dependent electroluminescence (EL) to evaluate the temperature stability of the μ LEDs.

II. EXPERIMENTAL DETAILS

Our amber InGaN LED epitaxial wafers were grown on *c*-plane patterned sapphire substrates via metalorganic vapor-phase epitaxy. The epitaxial structures have been reported in our previous study [16]. The thick GaN template [16] and hybrid InGaN QWs [20] were used to reduce the lattice mismatch of the InGaN amber QWs. The n-Al_{0.03}Ga_{0.97}N layer could realize an extremely low resistivity by high Si doping [21]. The schematic structure of InGaN μ LEDs is shown in Figure 1(a). Indium tin oxide (ITO) was deposited as the transparent conductive layer, and a two-step annealing with and without O_2 gas was done to achieve ohmic contacts with p-GaN [22]. The sheet resistivity of ITO layers could be further improved after the second annealing without O_2 gas. The µLED mesa was formed by etching through the ITO layer, InGaN QWs, and InGaN/GaN superlattices (SLs) to the n-type Al_{0.03}Ga_{0.97}N layer using inductively-coupled plasma. Before fabricating the n- and p-electrodes (Cr/Pt/Au), a SiO₂ layer was deposited using plasma-enhanced chemical vapor deposition to passivate the μ LED sidewalls. This SiO₂ layer could also serve as an isolated layer between the p-electrode and n-AlGaN.

The morphology of μ LEDs was examined via a scanning electron microscope (SEM). The μ LEDs were characterized at a probe station using a semiconductor parameter analyzer. The EL properties were measured under different currents at stage temperatures ranging from 295 K (room temperature) to 373 K.

III. RESULTS AND DISCUSSION

Figure 2(a) shows the top-view SEM image of a $47 \times 47 \ \mu m^2 \mu LED$. The n-electrode was around the four sidewalls of the μLED , and the p-electrode on ITO was designed as a cross shape. The designs of both the n- and p-electrodes were expected to guarantee uniform current injection into the μLED . Because the p-electrode extended from the bottom to the top of the μLED , the SiO₂ isolated layer covering the sidewall of the μLED was critical to avoid the connection between the p-electrode and the n-AlGaN layer.



Fig. 2. (a) Top-view SEM image of a 47 \times 47 μ m² InGaN μ LED. (b) Absolute current and current densities of a typical μ LED at the different bias voltages. (c) Measurement configuration picture of our μ LEDs. (d) EL spectra of a μ LED at 5-100 A/cm². The inset is the emission image at 5 A/cm².

The |I|-V curve was measured under the applied voltage ranging from -4 to 4 V. The absolute current was plotted on a logarithmic scale as shown in Figure 2(b). At a forward voltage below 1 V, the absolute current was at the detection floor. After increasing the forward voltage above 1 V, the current was increased linearly with two different slopes on the semi-logarithmic scale. The first linear part corresponded to the tunneling leakage current [23], while the second linear part was the typical operation region of a p-n junction diode. The transition point between the two linear parts, which was regarded as the turn-on voltage, was around 2.5 V. This |I|-V behavior was quite similar to other yellow/red InGaN μ LEDs [6], [14]. The operating voltage at 20 A/cm² was around 3.1 V.

At the reverse voltage, the reverse current also stayed at the detection floor. However, it started to increase after the reverse voltage increased above -3 V. The increment of the reversed currents illustrates that some leakage channels existed in our InGaN μ LEDs, which might be caused by the defects in the InGaN active region [24] and the Shockley-Read-Hall (SRH) non-radiative recombination at the μ LED sidewalls [9].

Figure 2(c) shows the EL measurement configuration of μ LEDs. μ LEDs were driven at the probe station, and the integrating sphere was located above the sample to collect the light output power of μ LEDs. Figure 2(d) shows the EL spectra of a μ LED at 5 to 100 A/cm². The typical single peaks can be observed for all EL spectra. The peak wavelength of the μ LED was 606 nm at 20 A/cm² (non-uniformity ~ 603–611 nm for 2- inch wafer). No additional blue peaks in this work demonstrated less In fluctuation and phase separation in the μ LED compared to previous works [16], [25]. The EL emission of the μ LED at 5 A/cm² in the inset of Fig. 2(d) exhibited non-uniform luminescence due to defects in the amber QWs.

The current density dependence of the peak wavelength and FWHM for the μ LEDs is shown in Figure 3(a). The peak wavelength of the μ LED exhibited a total 33-nm blue-shift



Fig. 3. (a) Peak wavelength and FWHM and (b) EQE and output power of a typical μ LED at different current densities based on on-wafer testing.

from 624 to 591 nm at 5 to 100 A/cm². However, the blueshift behavior was different at low and high current densities. At the current densities <40 A/cm², the blue-shift of the peak wavelength was as large as 26 nm, which was caused by the strong QCSE and band filling effect in high-In-content InGaN QWs [8], [11], [26]. However, at the current densities above 40 to 100 A/cm², the band filling effect should have been negligible, and the QCSE was also partially compensated. Therefore, the peak wavelength of the μ LED had a slight blue-shift of 7 nm, as shown in Figure 3(a). Because the QCSE and the band filling effect were respectively originated from the in-plane strain and In fluctuation in InGaN QWs, the strain relaxation and the improvement of the InGaN crystal quality were vital for suppressing this large blue-shift.

The FWHM at the current density below 20 A/cm² remained 50-51 nm, which was comparable to the best values of other InGaN orange and red LEDs [15], [27]. However, the FWHM increased to around 56 nm with a current density up to 100 A/cm². Our previous work found that the reason was the heat generation in devices under high direct current injection [25].

The output power of the μ LED increased almost linearly with the current density. At 20 A/cm², we obtained an output power of 5 μ W at the wavelength of 606 nm. The output power density was calculated as 2.26 mW/mm², which corresponded to the peak on-wafer EQE of 0.56% (Fig. 3(b)).

To estimate the absolute EQE in the integrating sphere, a green μ LED in the same size was used to obtain the calibration factor for the on-wafer testing and measurement in the integrating sphere. This calibration method was also used in other works [6], [14]. The output power of the green μ LED (bare chip without resin) measured in the integrating sphere was enhanced by ~2.17 compared to that measured by the on-wafer testing. Therefore, we could expect that the absolute peak EQE of our amber μ LEDs was estimated to exceed 1.2%. At the current density above 20 A/cm², the on-wafer EQE in Fig. 3(b) exhibited a typical behavior of the efficiency droop, which was calculated around 10% from 20 to 100 A/cm².

The characteristic temperature indicates the temperature stability of μ LEDs [27]. A larger characteristic temperature implies a weaker temperature dependence. The EL intensity of the μ LEDs at 20 to 100 A/cm² at different stage temperatures from 295 (RT) to 373 K was normalized by EL intensity at RT and plotted on a logarithmic scale in Figure 4(a). The characteristic temperature could be obtained using the following formula shown below:

$$I = I_{T=295K} \exp\left(-\frac{T - 295K}{T_0}\right)$$
(1)



Fig. 4. (a) EL integral intensity of a typical μ LED at different current densities. (b) Fitted characteristic temperatures at different current densities.

where *I* is the normalized EL intensity, $I_{T=295K}$ is the EL intensity at 295 K, *T* [K] is the stage temperature, and T_0 [K] is the characteristic temperature.

By fitting the experimental data in Figure 4(a), we obtained the characteristic temperatures and their fitting errors at 20 to 100 A/cm² in Figure 4(b). The characteristic temperature was 50–80 K at the current density < 60 A/cm², but increased strongly to 120–140 K at 80 to 100 A/cm². We found that the characteristic temperature of InGaN μ LEDs was much lower than our standard red LEDs (higher than 300 K) [25], which was caused by more SRH non-radiative recombination at the sidewalls of μ LEDs compared to standard LEDs.

Furthermore, the SRH non-radiative recombination was also the main reason for the current density dependence of the characteristic temperature for InGaN μ LEDs [28]. At this point, we believe that the SRH non-radiative recombination included not only the surface recombination at the sidewalls but also the defect-related non-radiative recombination in high-In-content QWs. The SRH non-radiative recombination could be saturated at high current densities. Therefore, the EL intensity of the μ LEDs at high current densities would be less influenced by the SRH non-radiative recombination and exhibited less thermal droop and higher characteristic temperatures.

IV. CONCLUSION

In summary, we demonstrated amber InGaN 47 \times 47 μ m² μ LEDs with a wavelength of 606 nm and an FWHM of 50 nm at 20 A/cm². A large blue-shift of 33 nm for the amber InGaN μ LEDs was observed at 5 to 100 A/cm². The peak on-wafer EQE was 0.56% (estimated to exceed 1.2% if measured in the integrating sphere) at 20 A/cm², corresponding to a high output power density of 2.26 mW/mm². The characteristic temperature was 50–80 K at 20 to 60 A/cm² but increased to 120–140 K at 80 to 100 A/cm². These higher characteristic temperatures under higher current densities were caused by the saturation of the SRH non-radiative recombination at high current densities.

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